

Fig. 1

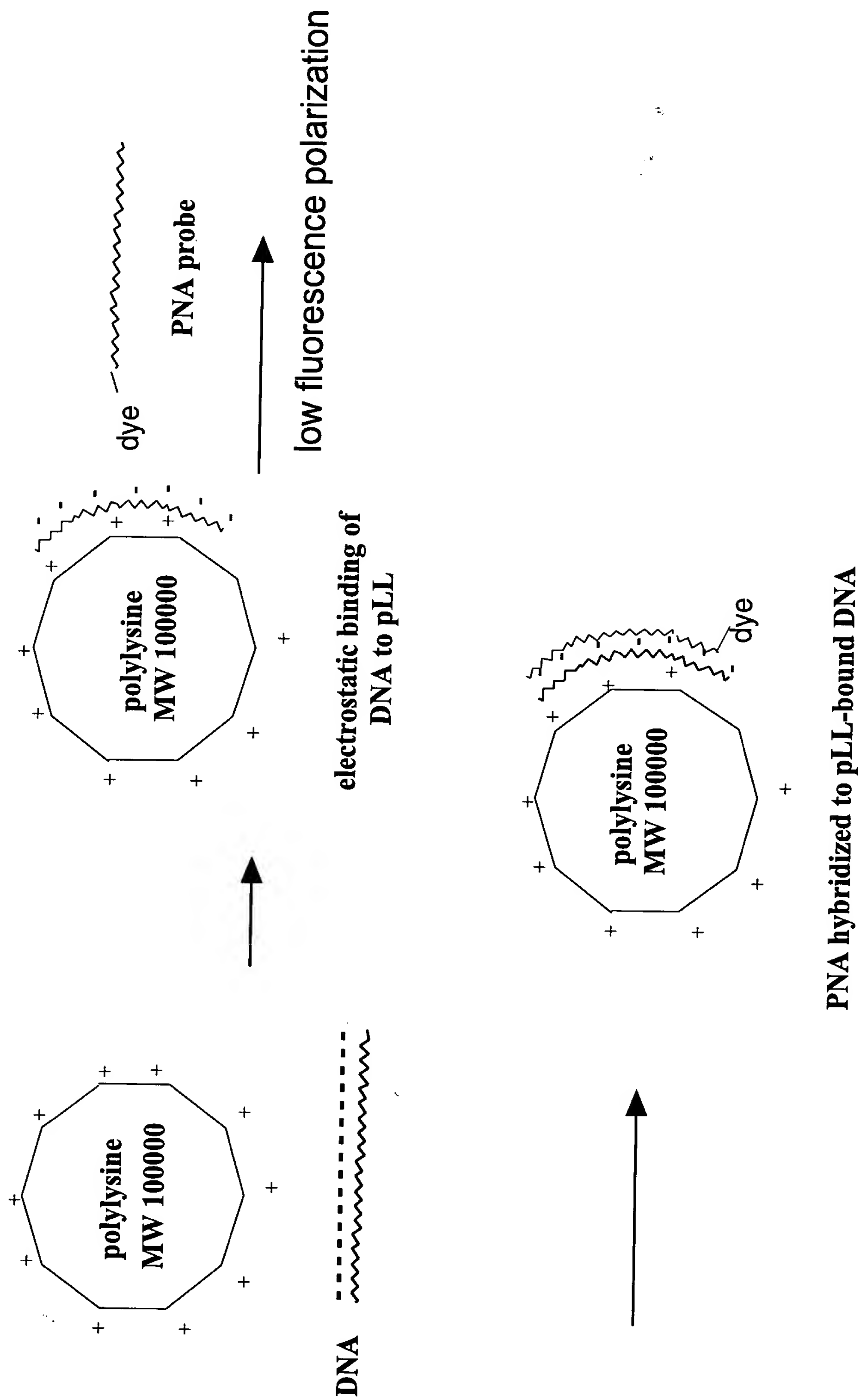


Fig. 2A

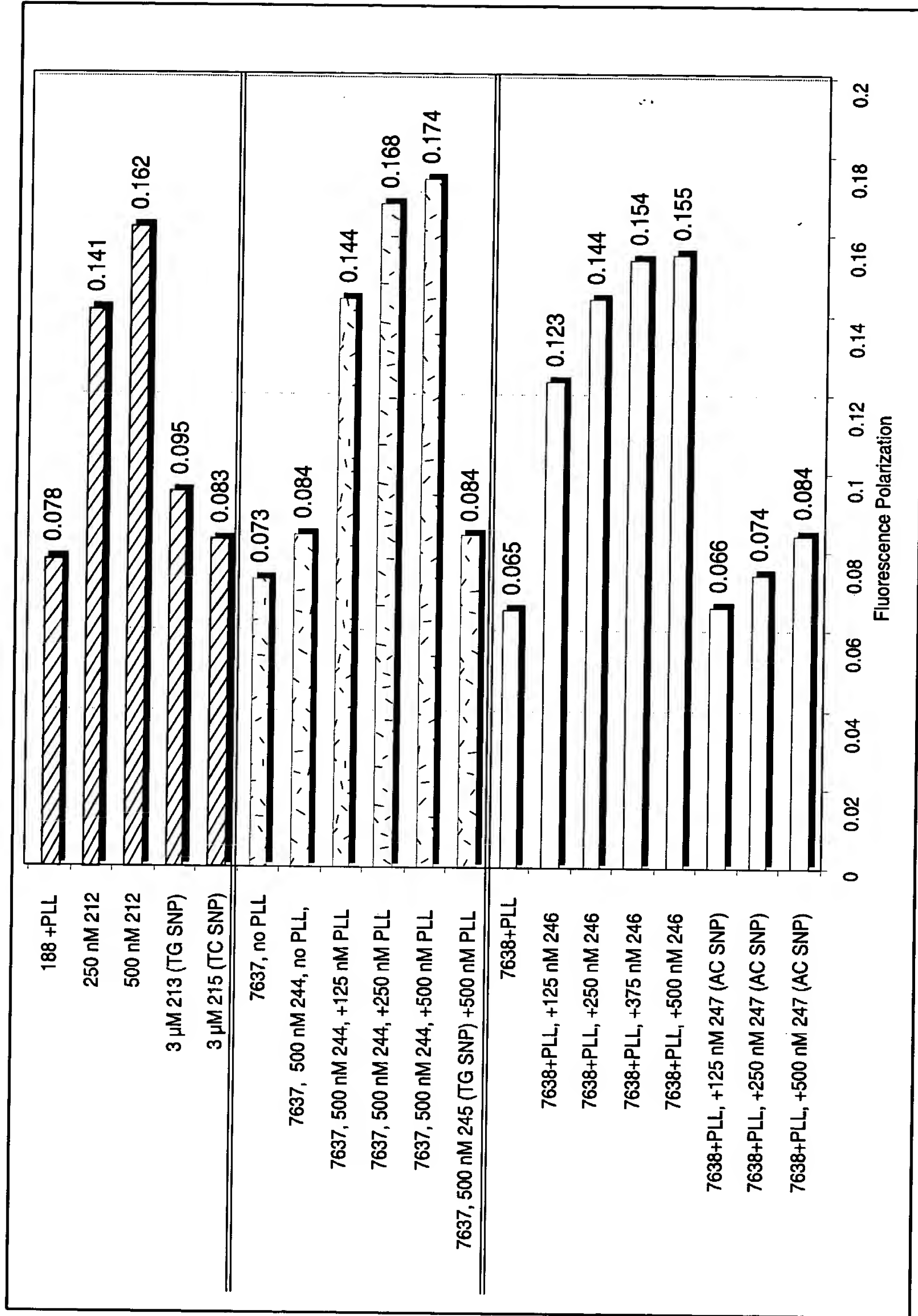


Fig. 2B

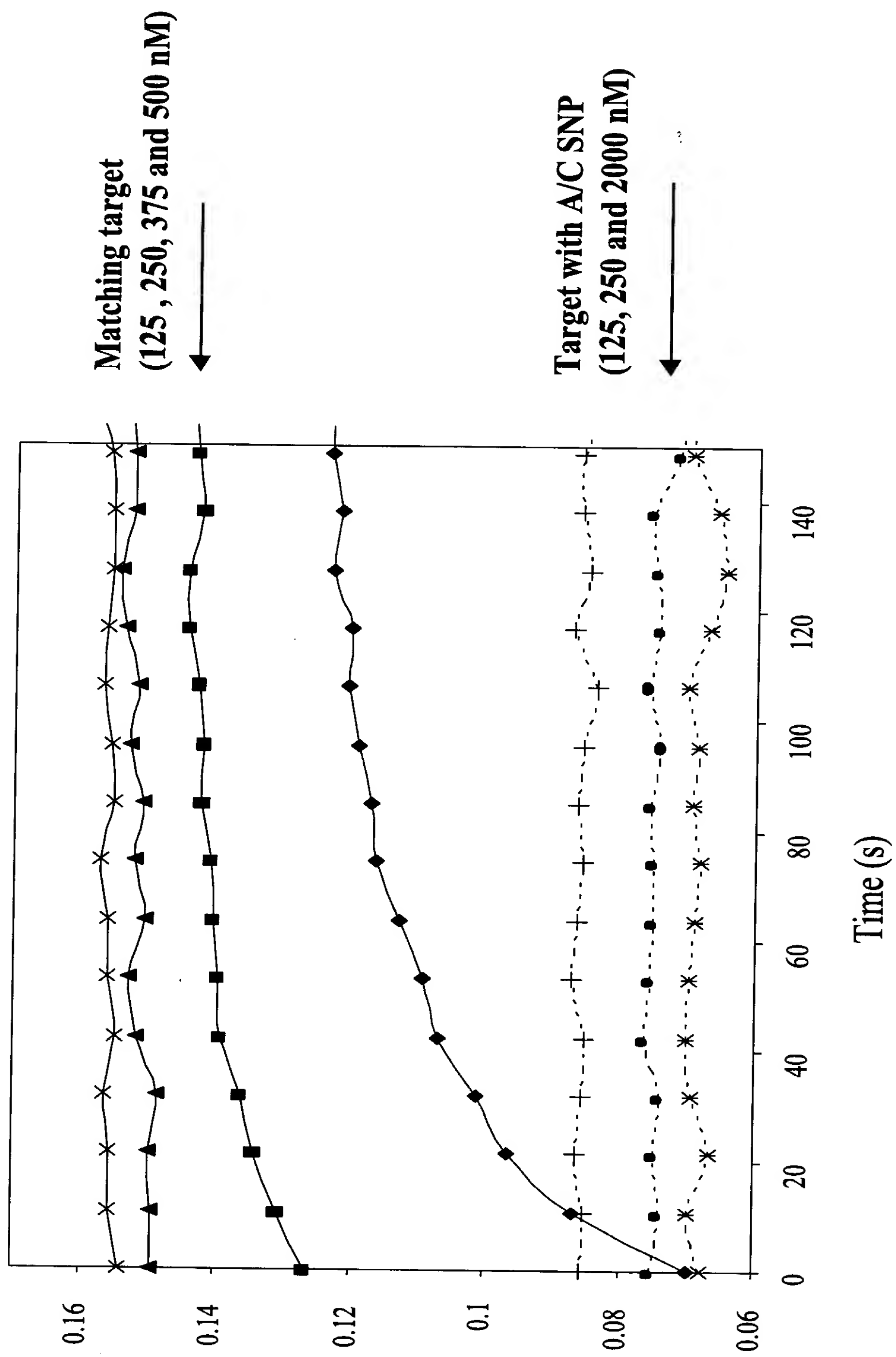
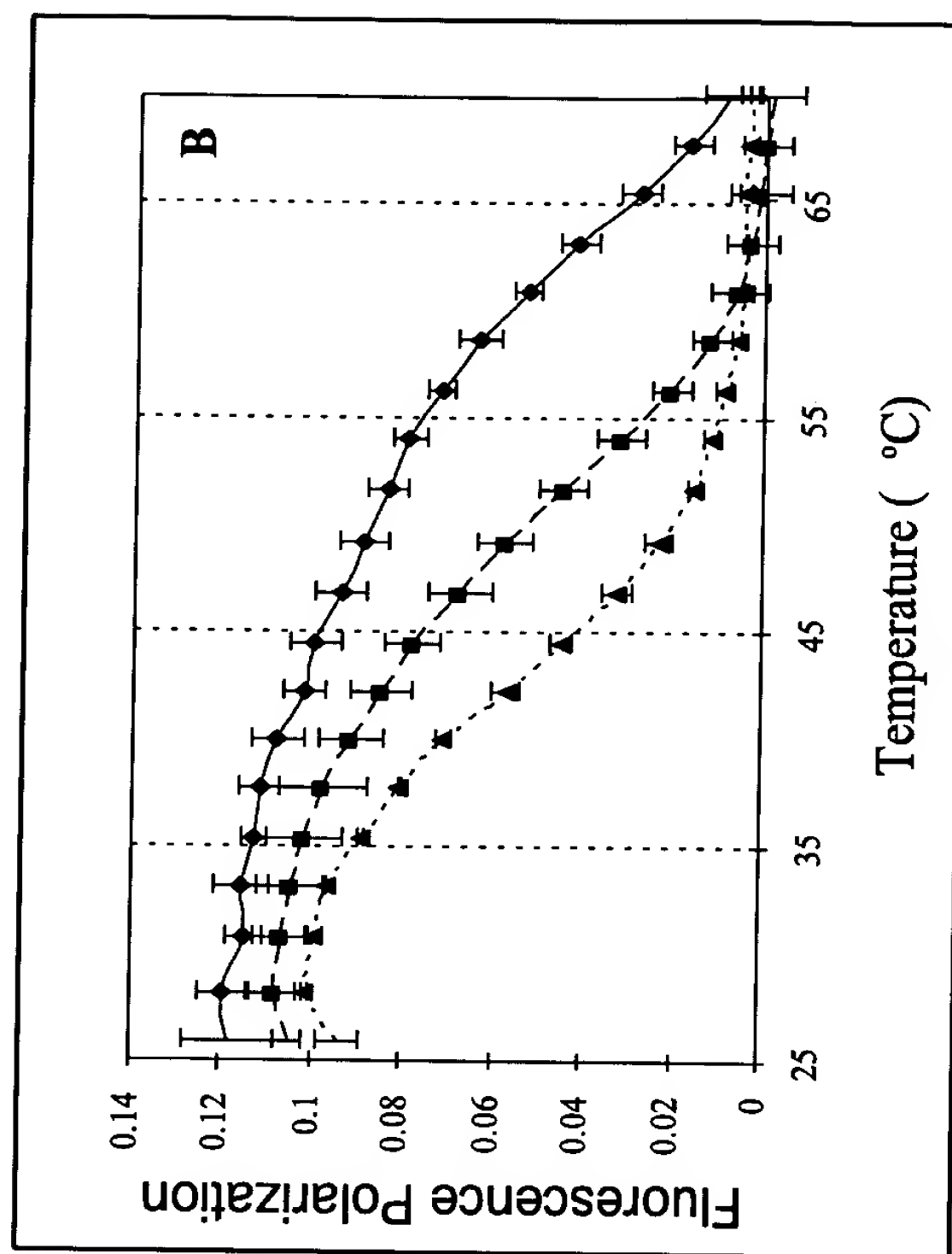
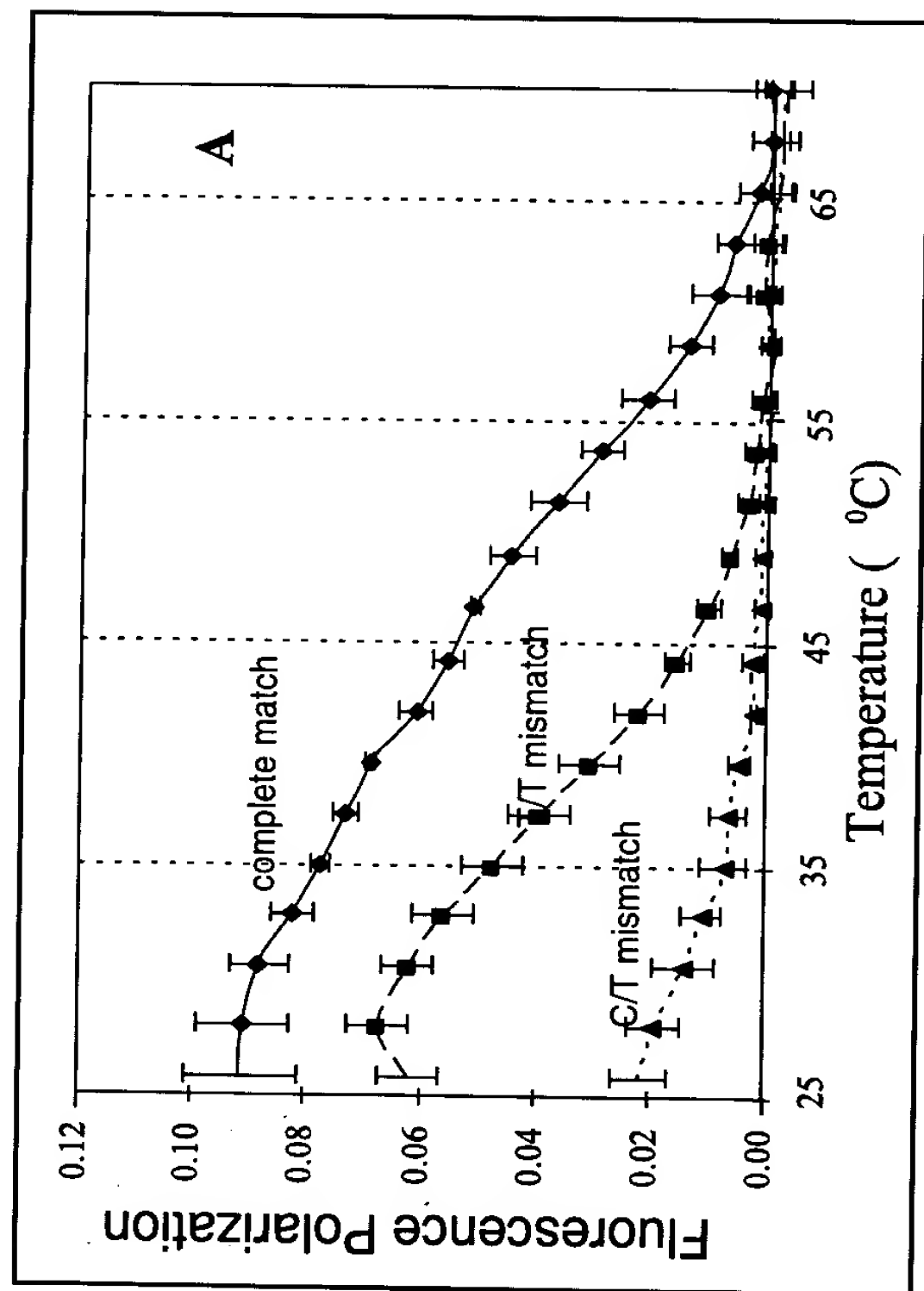


Fig. 2C



- A. PNA probe 188 (9mer)
 B. PNA probe 201 (11mer)
 C. PNA probe 202 (13mer)

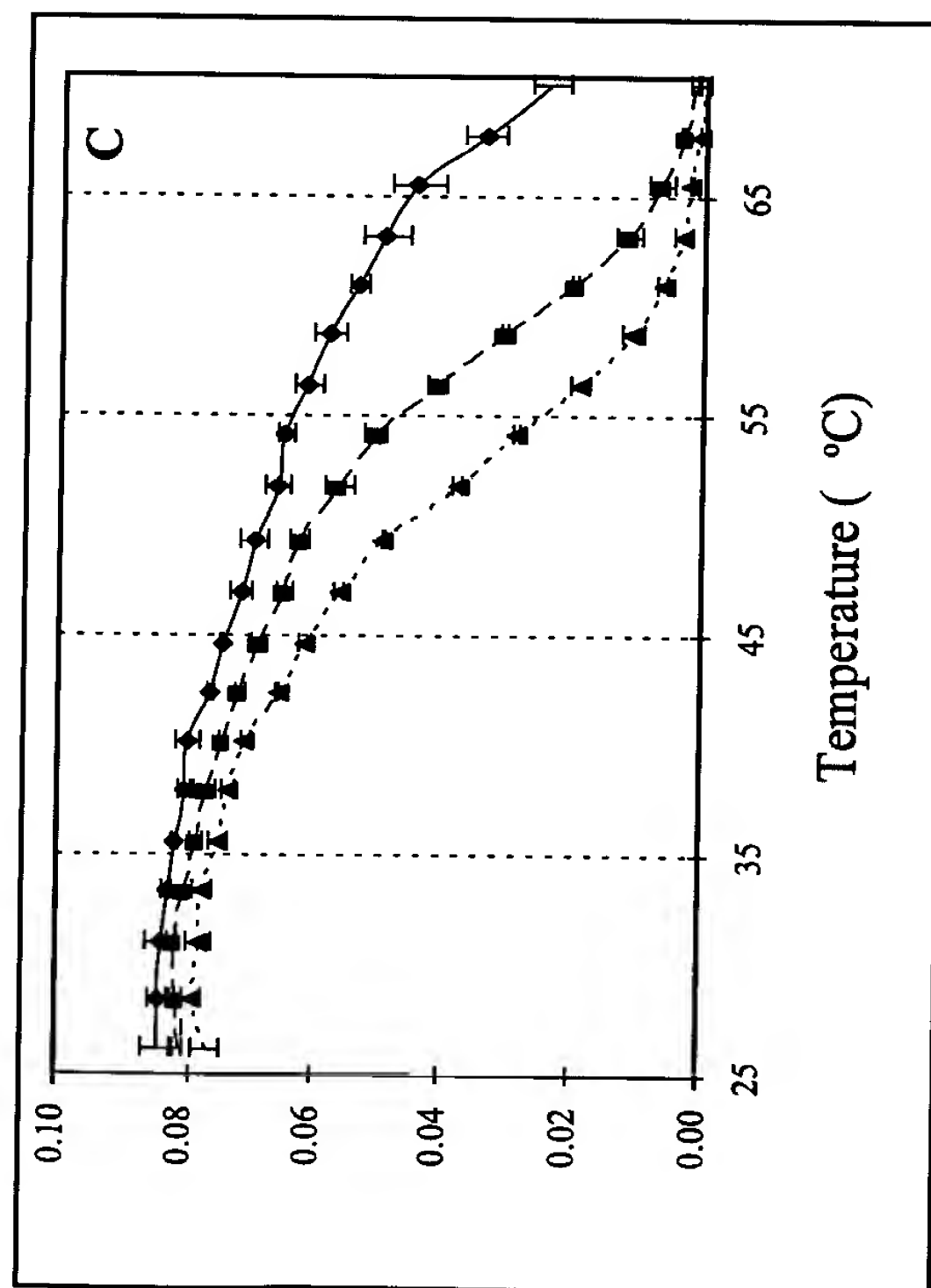


Fig. 2D

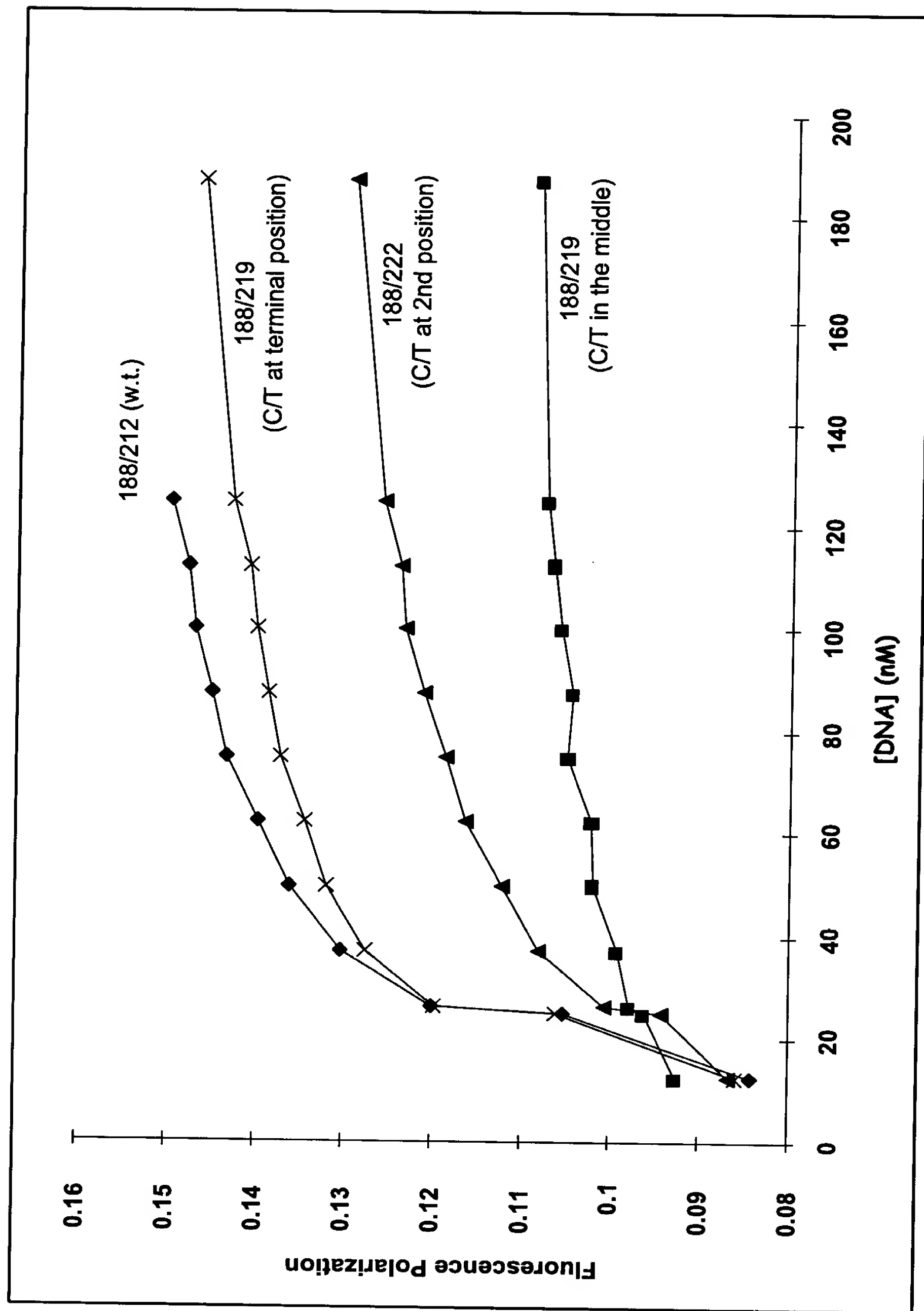


Fig. 2E

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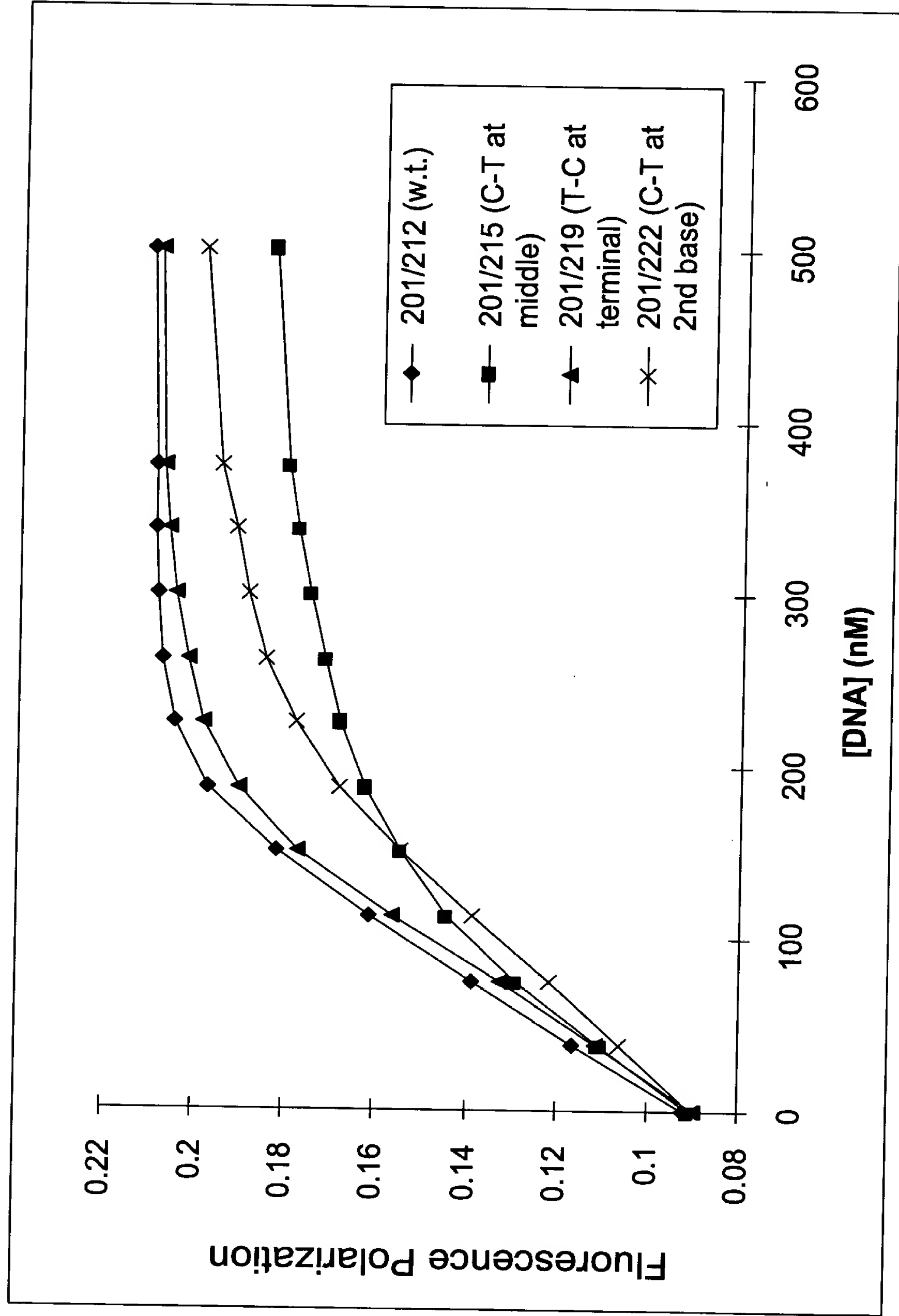


Fig. 3A

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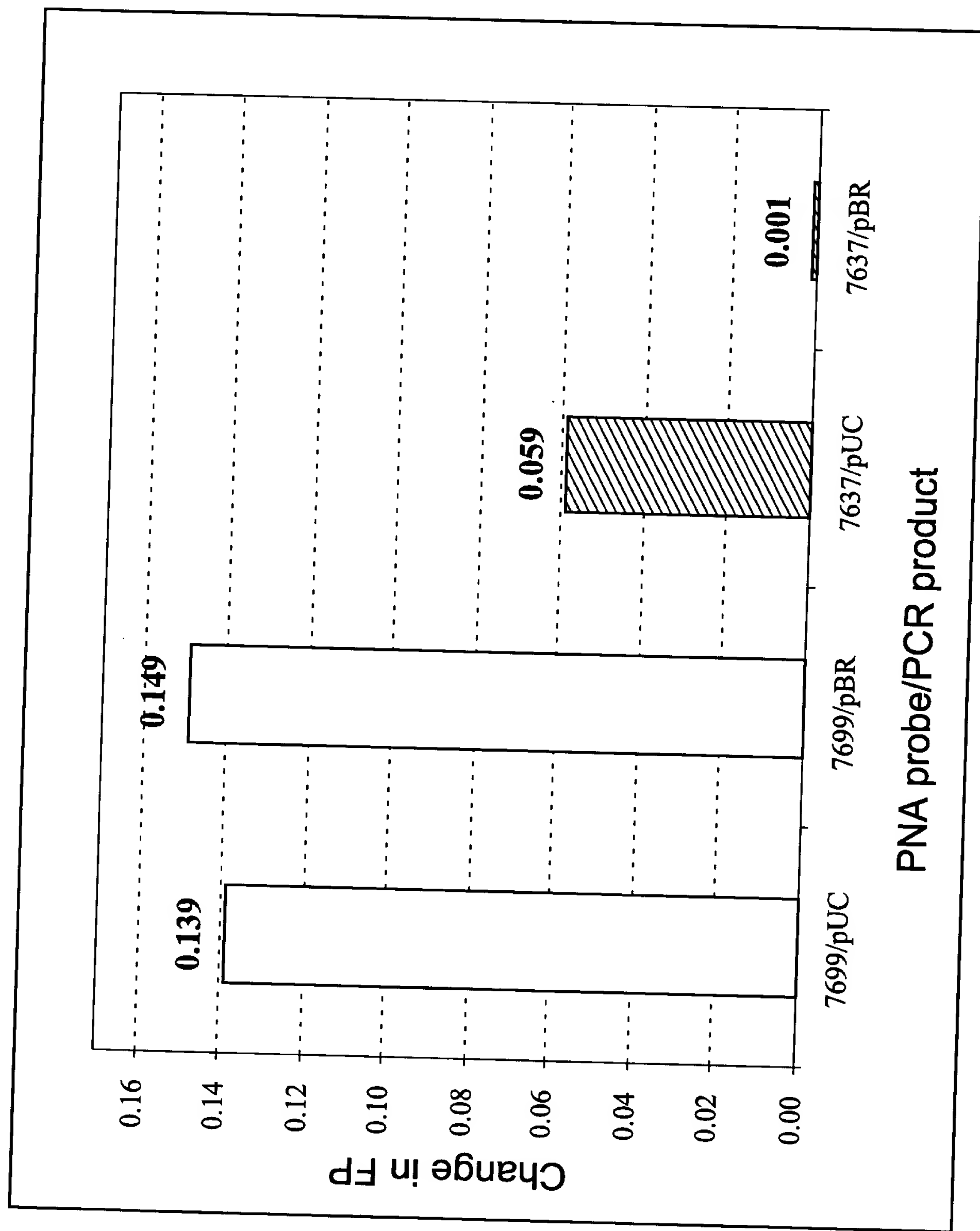


Fig. 3B

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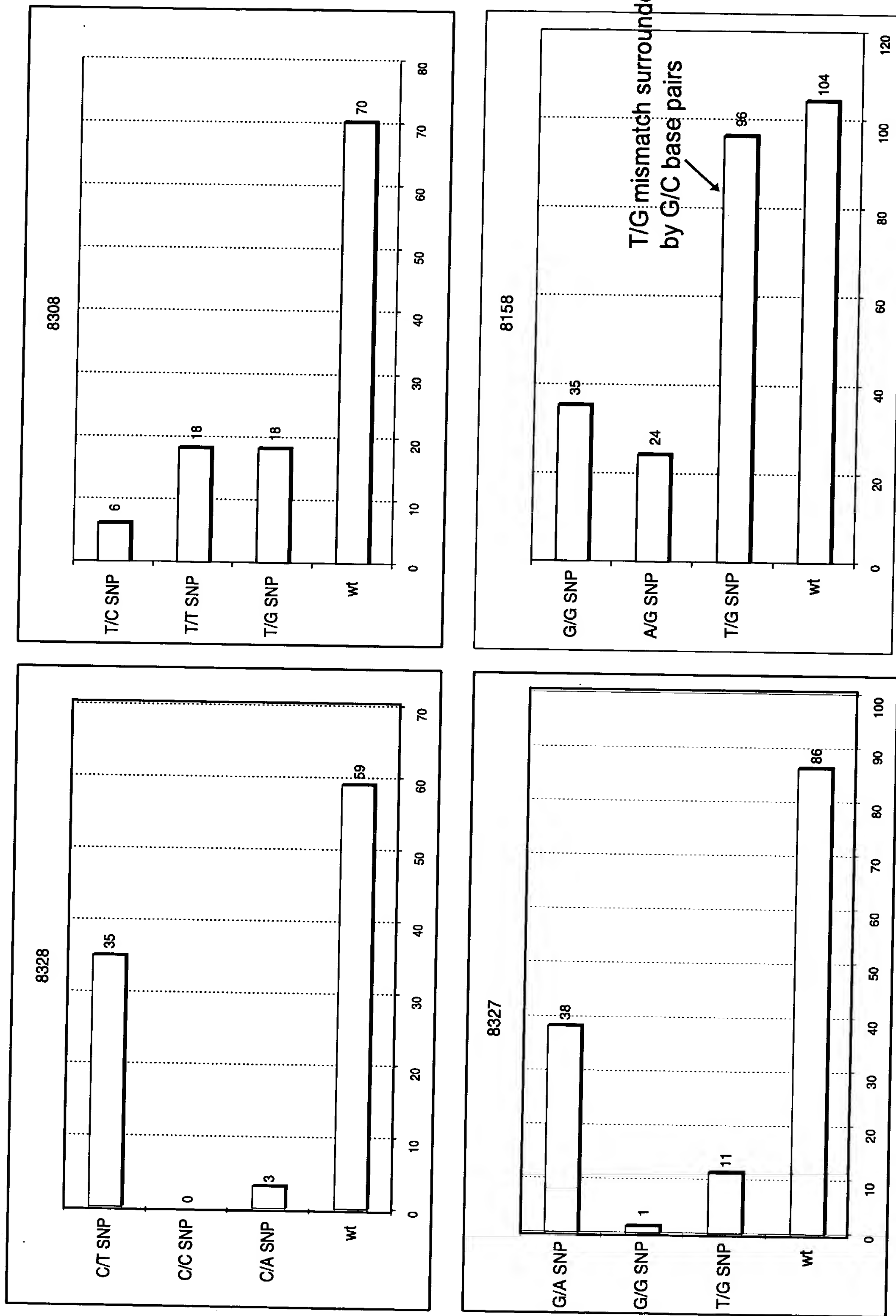


Fig. 3C

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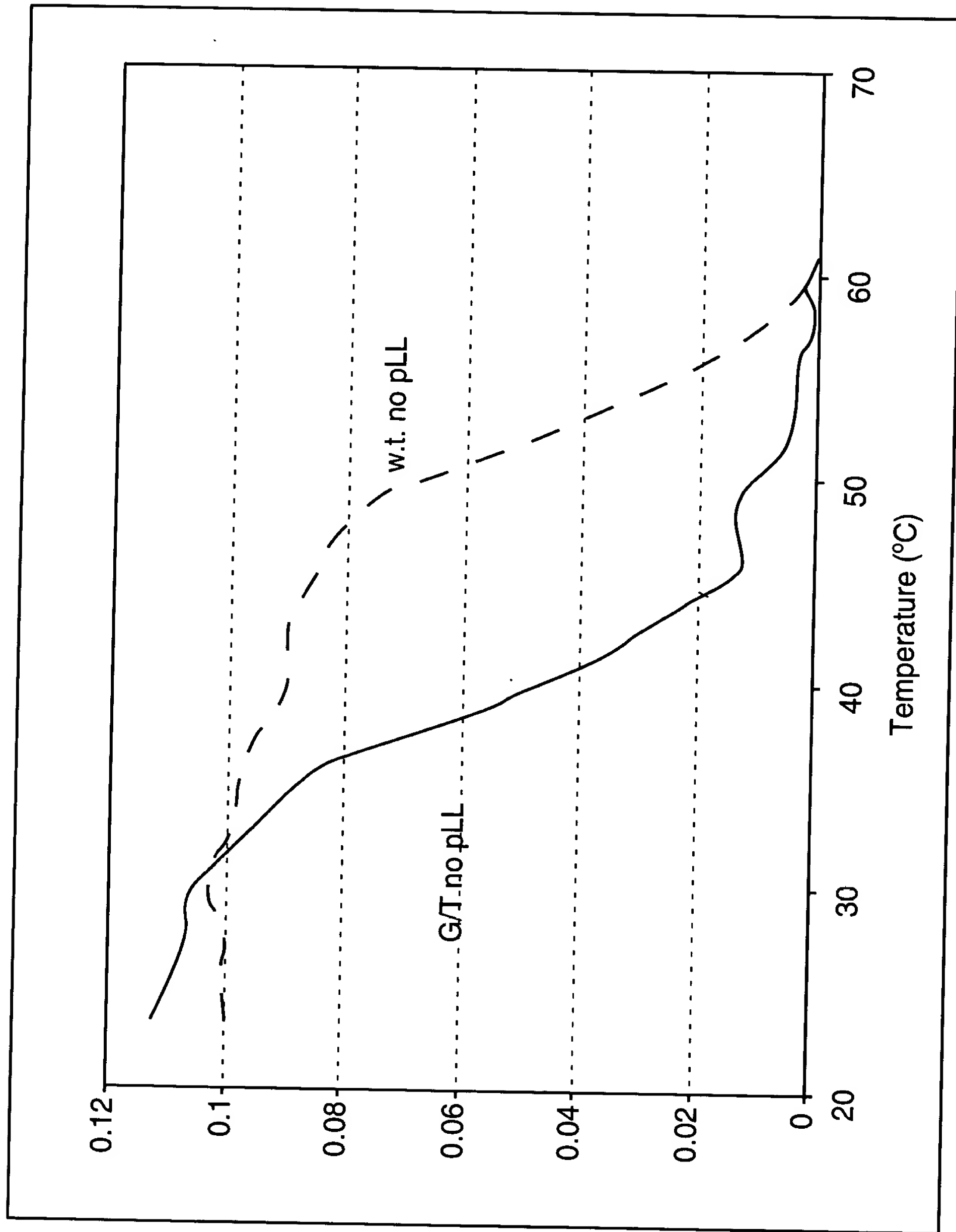


Fig. 3D

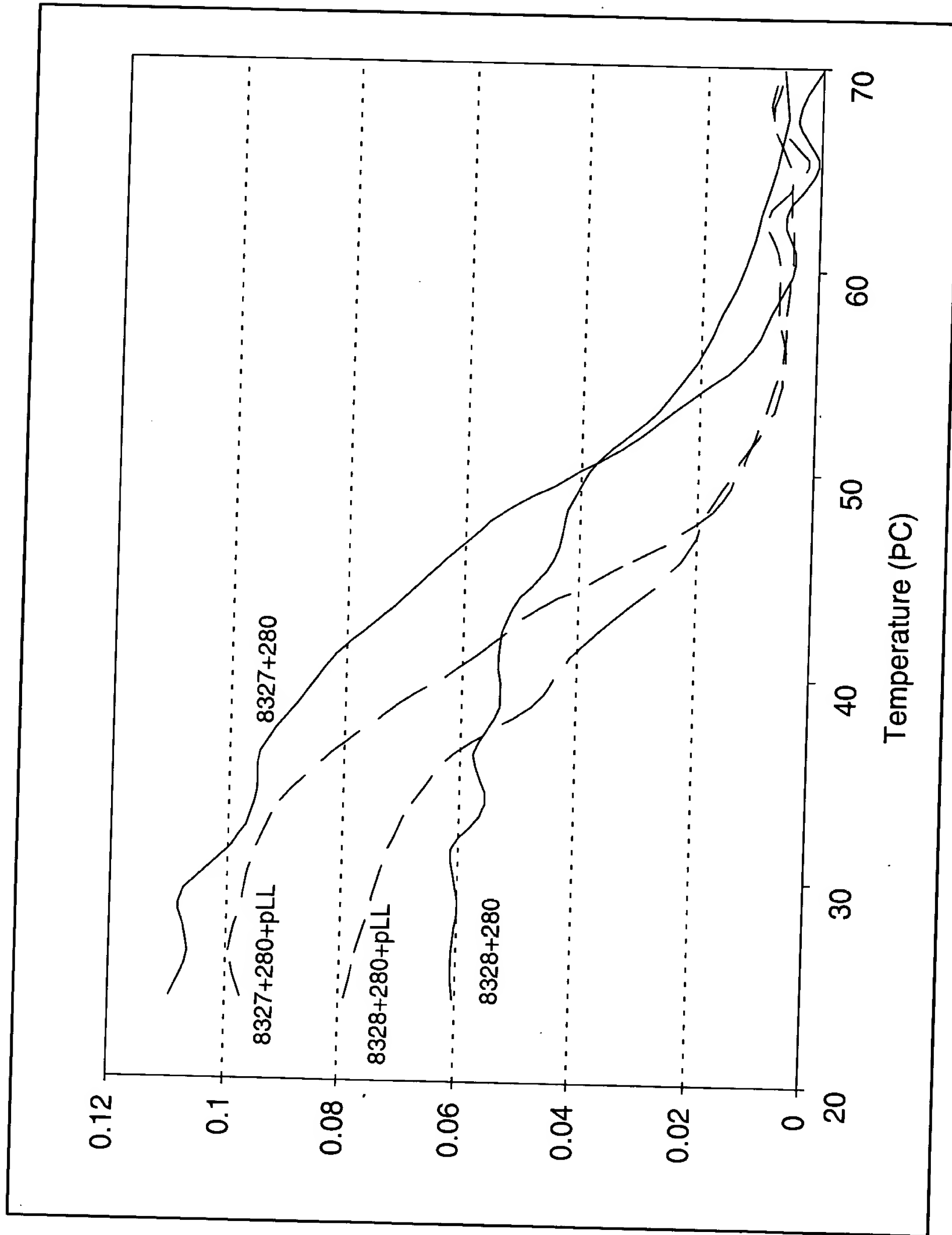


Fig. 4A

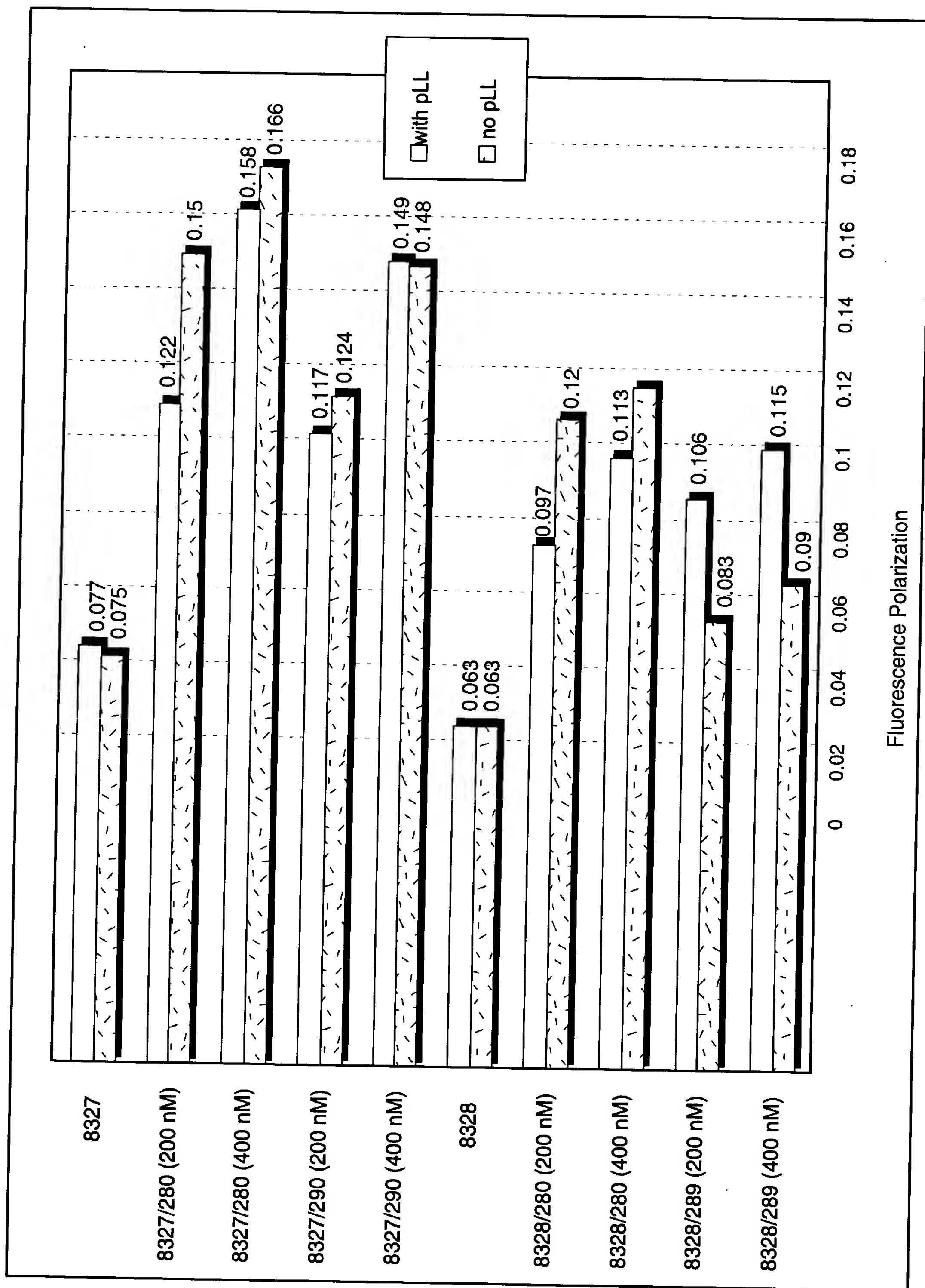


Fig. 4B

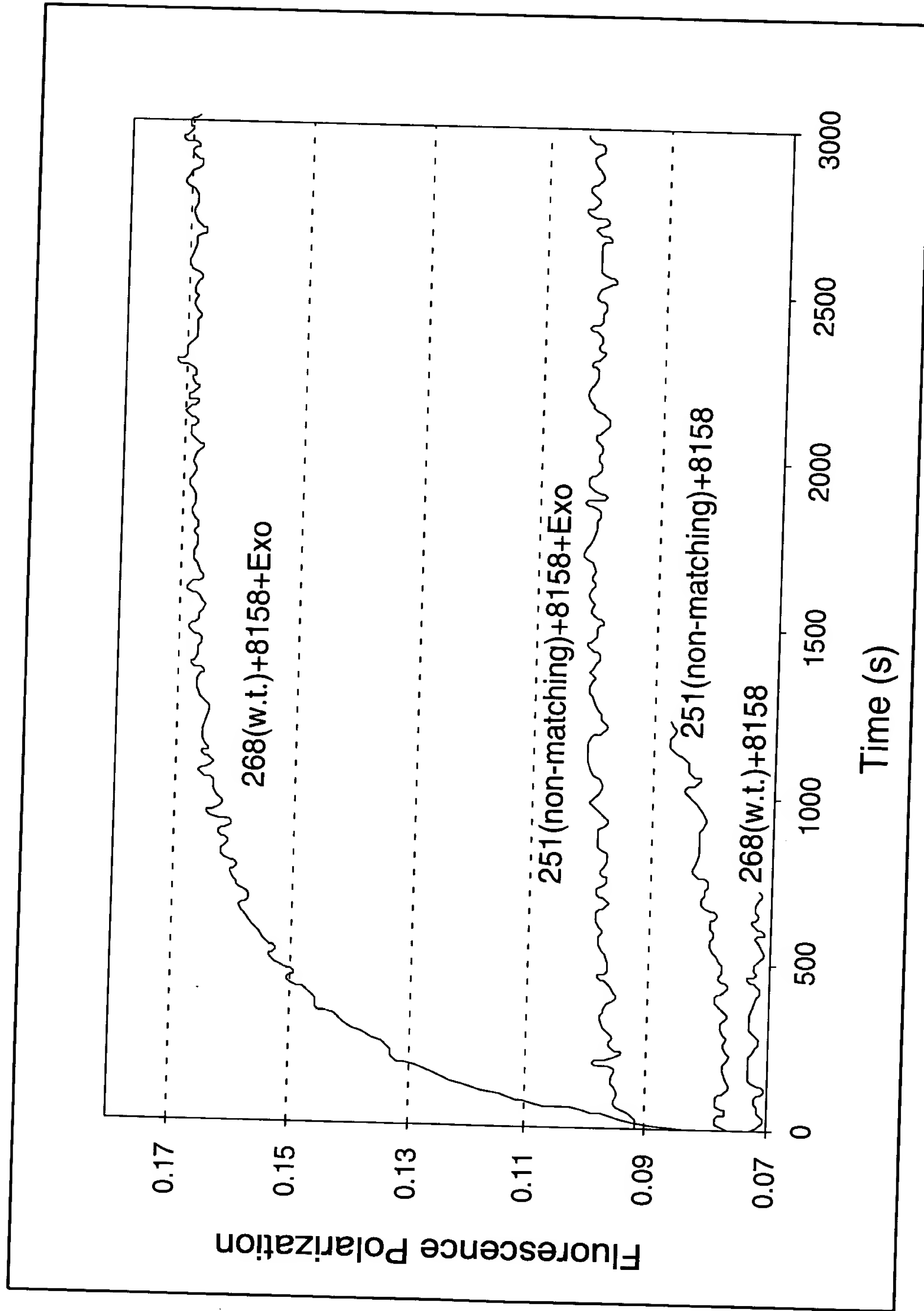


Fig. 4C

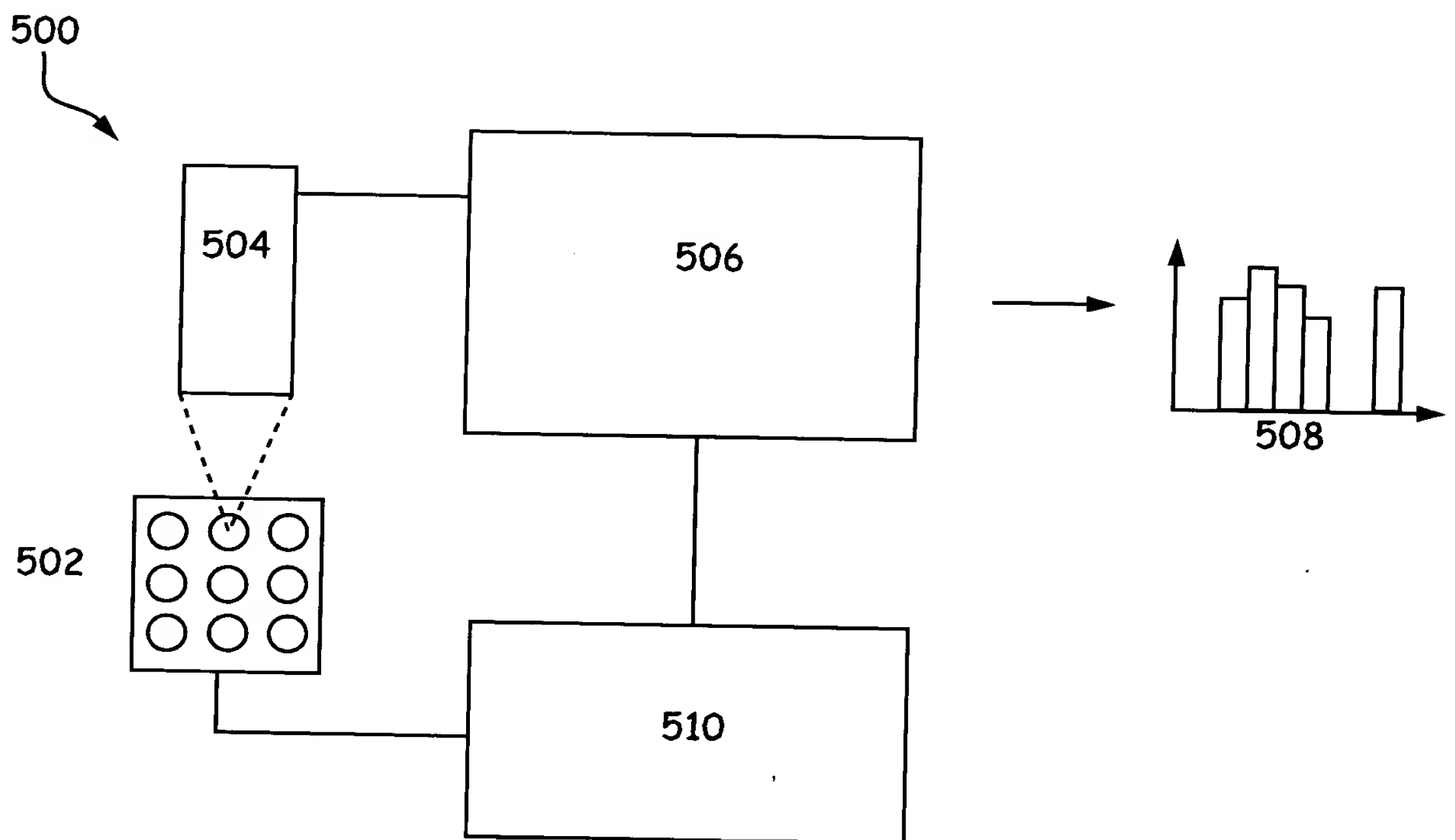


Fig. 5

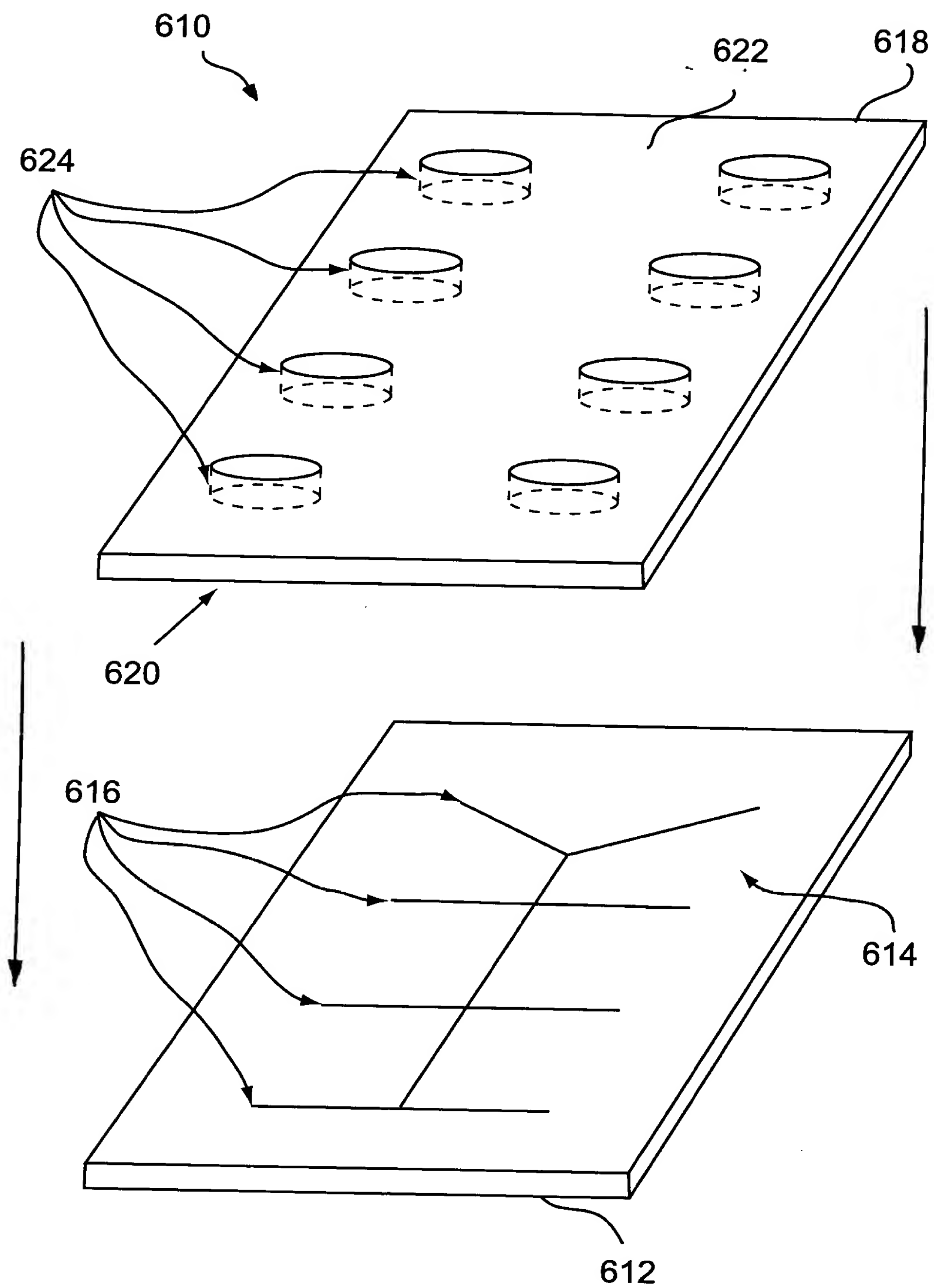


Fig. 6

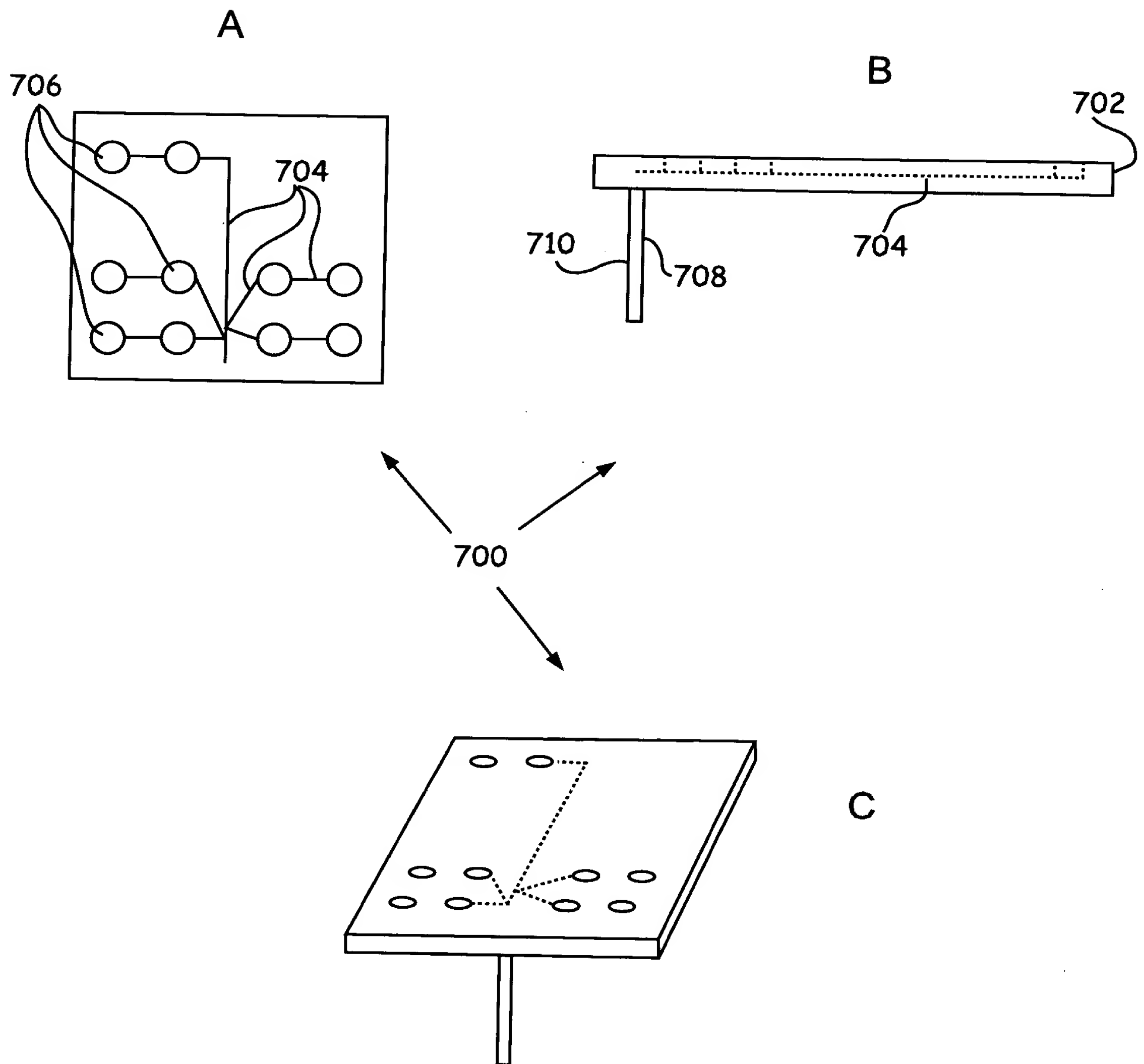


Fig. 7

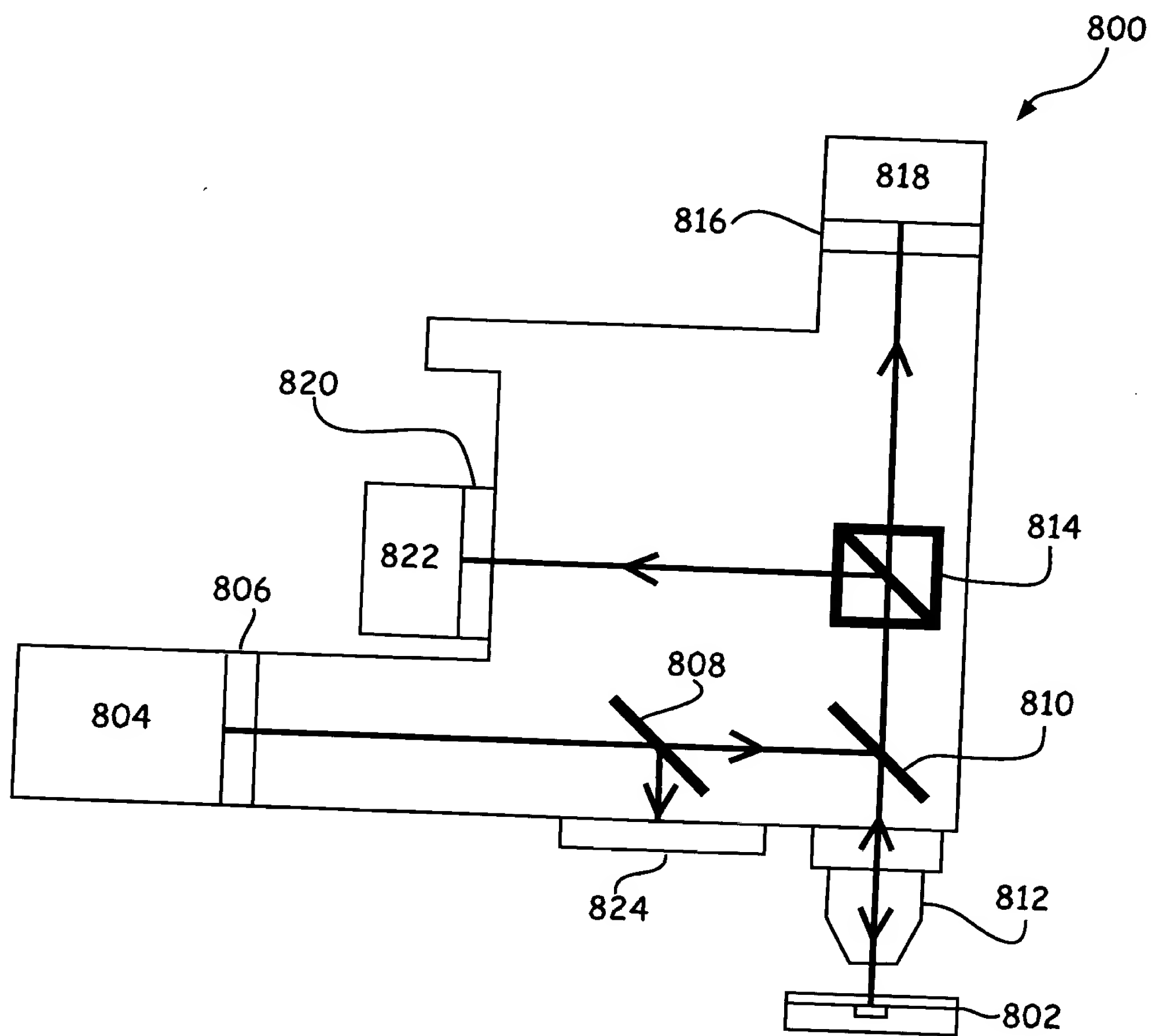


Fig. 8

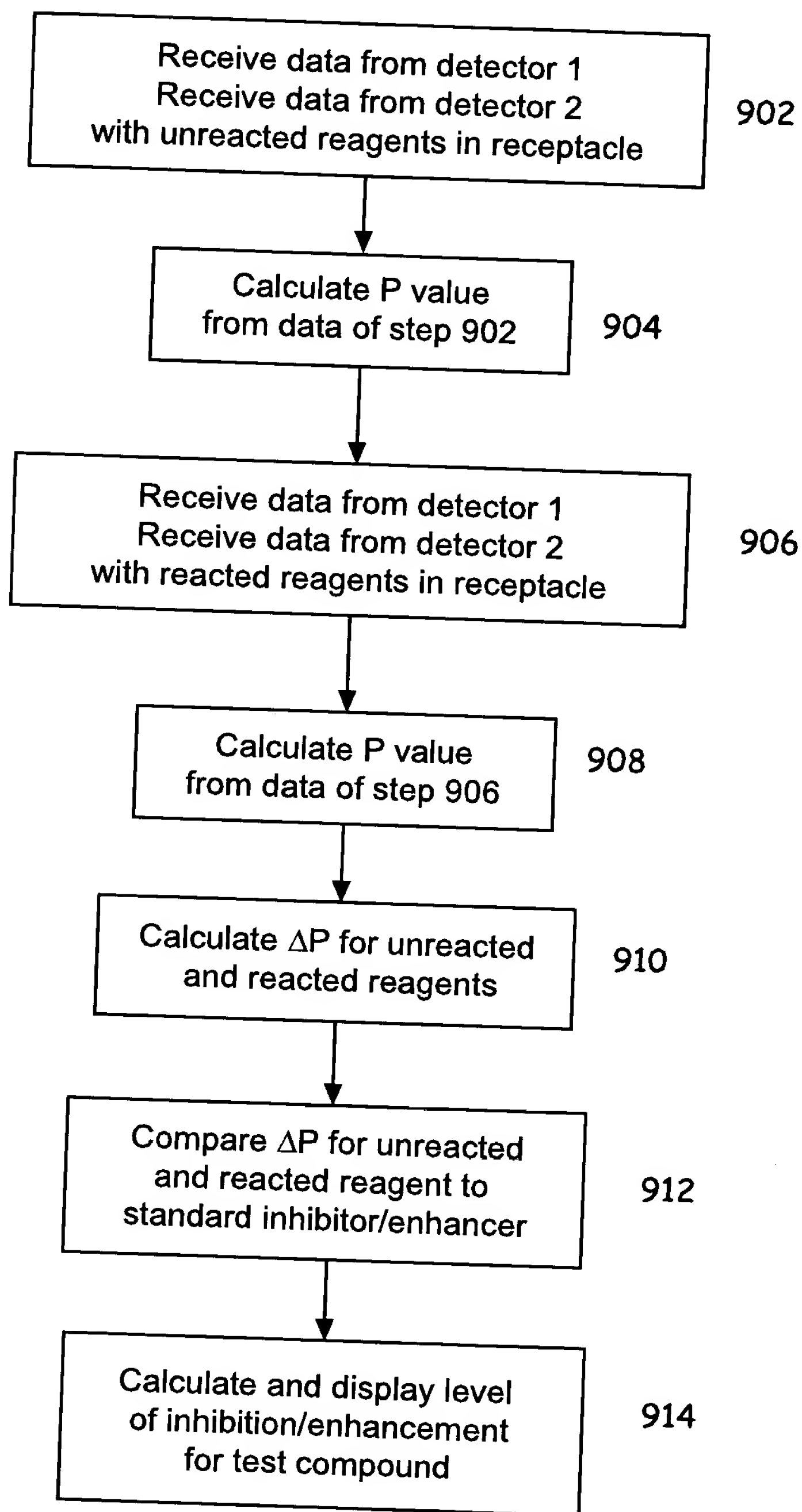


Fig. 9

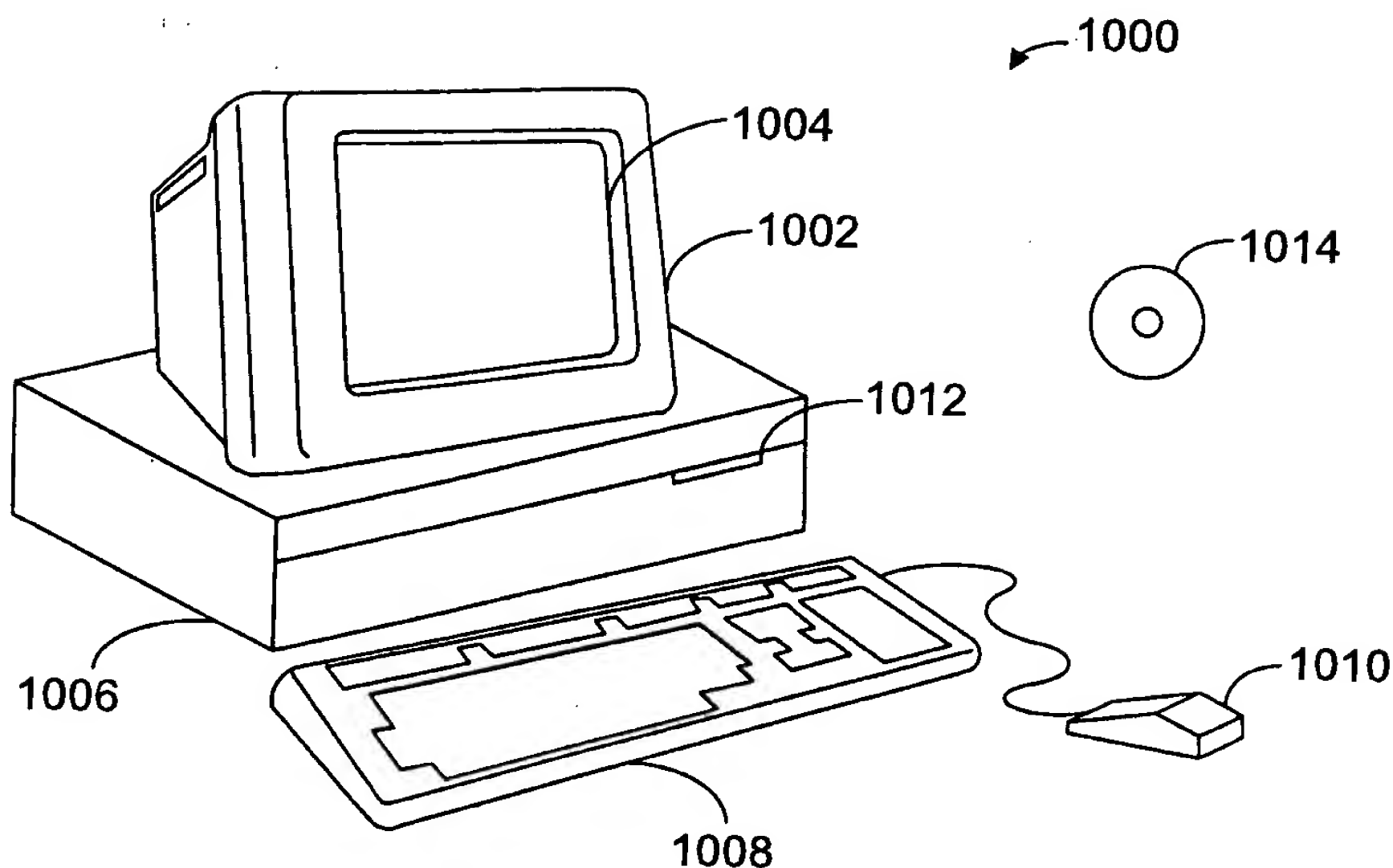


Fig. 10A

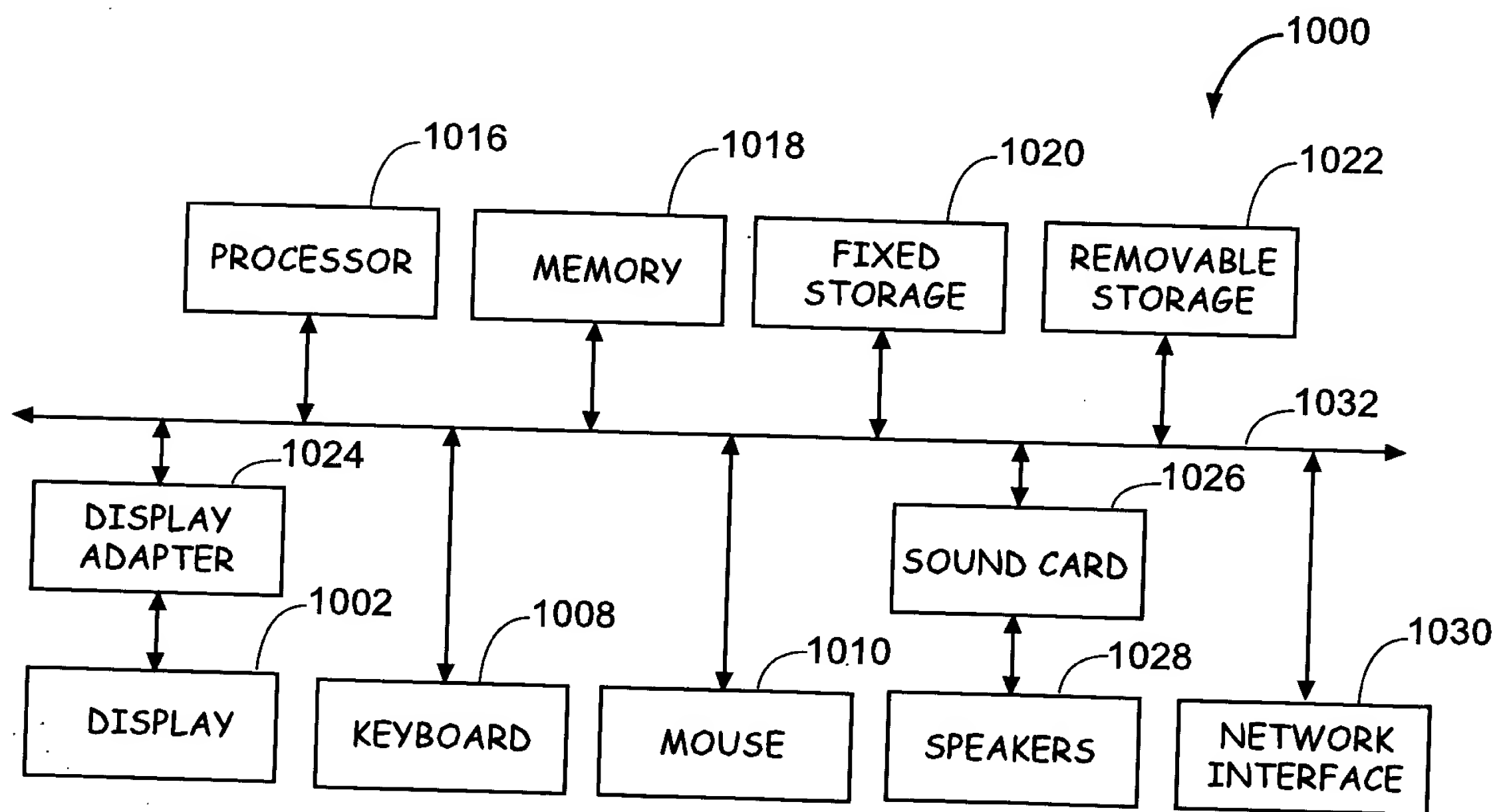


Fig. 10B

FIG. 11 is a perspective view of a system 1100 for processing a substrate 502. The system 1100 includes a substrate 502 with a grid of circular features 504. A probe 700 is positioned above the substrate 502, with a probe tip 708. The probe 700 is connected to a control unit 506 via a cable 508. The control unit 506 is connected to a computer 510. The system 1100 is used for measuring the height of the circular features 504 on the substrate 502.

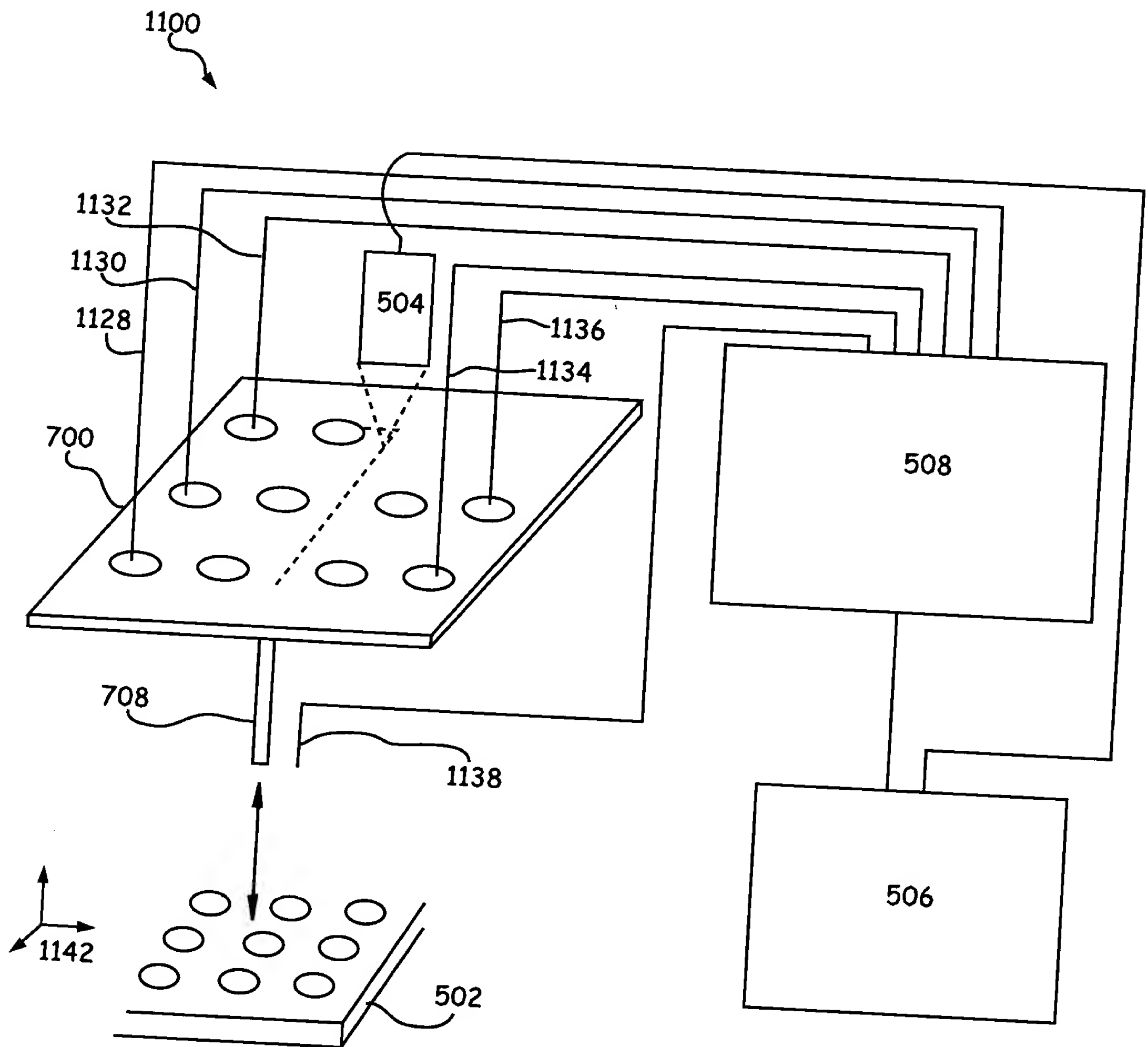


Fig. 11

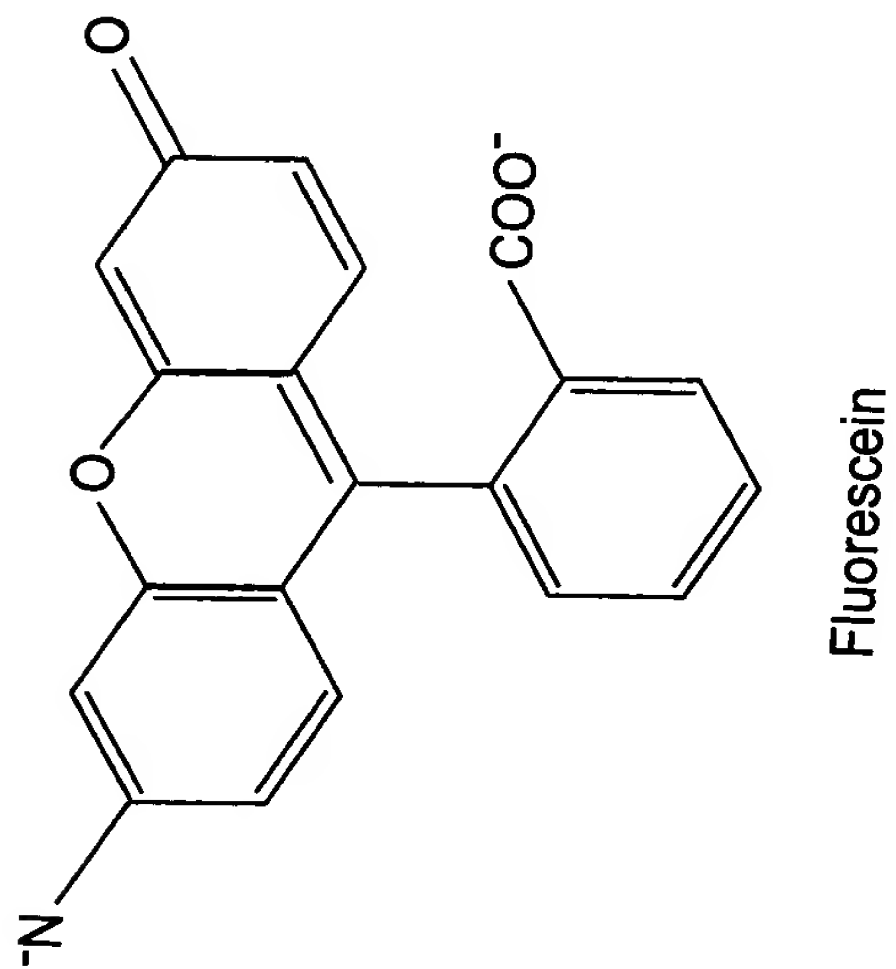
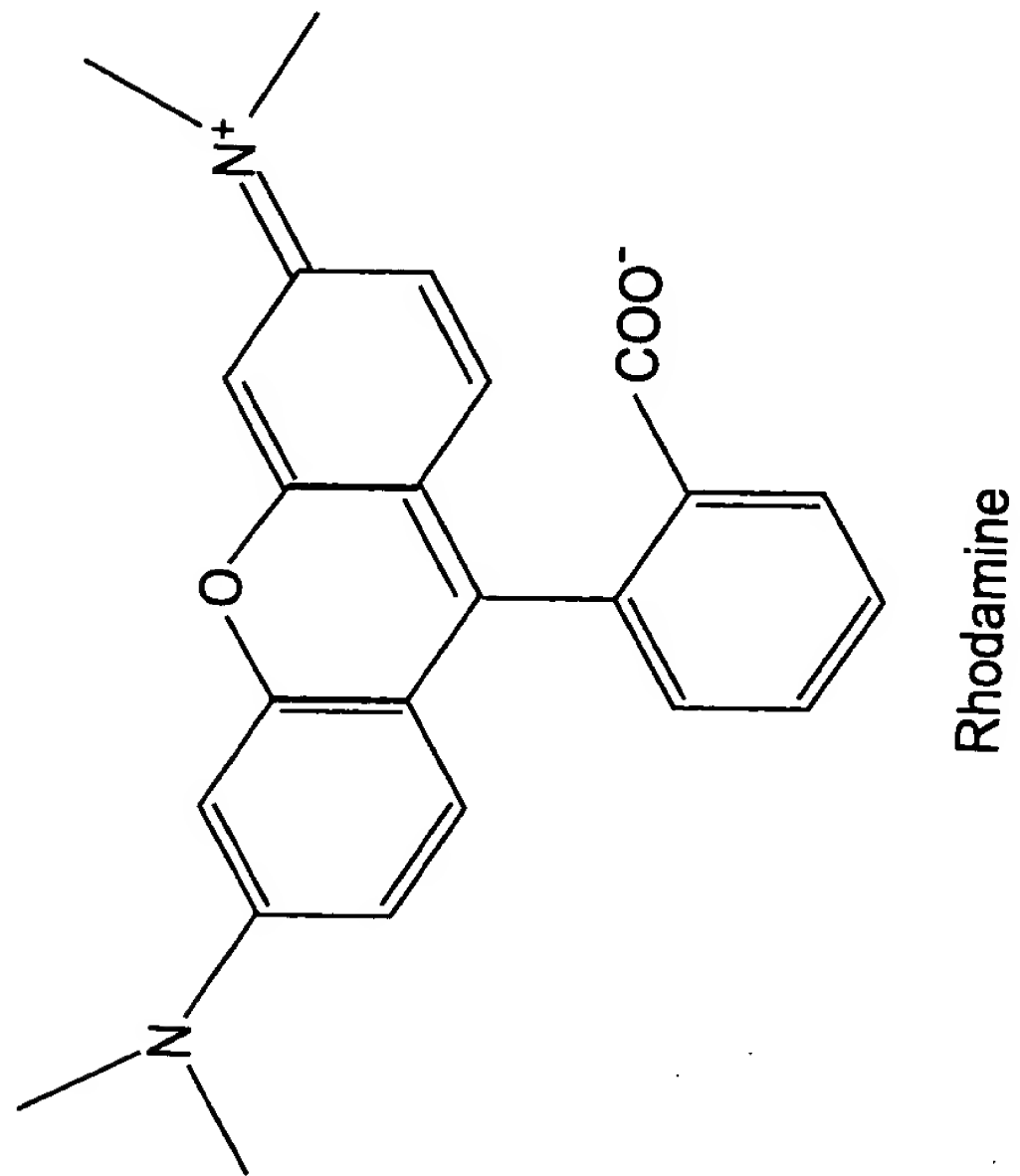


Fig. 12